Lianhua Jin

List of Publications by Year
in descending order

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72 papers	372 citations	933447 10 h-index	940533 16 g-index
72 all docs	72 docs citations	72 times ranked	212 citing authors

#	Article	IF	Citations
1	Characterization of thin films from reflection and transmission ellipsometric parameters. Japanese Journal of Applied Physics, 2022, 61, 018004.	1.5	1
2	Lateral ellipsometry resolution for imaging ellipsometry measurement. Japanese Journal of Applied Physics, 2021, 60, 058003.	1.5	5
3	3D profile measurement of openings with optical caliper. , 2021, , .		0
4	Imaging ellipsometry measurement noises associated with non-uniform retardation of the compensator. Optical Review, 2020, 27, 73-80.	2.0	3
5	Design of a spectroscopic imaging ellipsometer. , 2020, , .		0
6	Ellipsometric Microscope â€•Design and Application of a Microscope for Oblique Observation of Samplesâ€•. Journal of the Japan Society for Precision Engineering, 2020, 86, 533-536.	0.1	0
7	Optical profilometry of cylindrical openings for transparent objects. , 2020, , .		0
8	Facile and Efficient Gas-Phase Pressure-Controlled Thermal Functionalization of Nanocrystalline Porous Silicon with 1-Hexene. ECS Journal of Solid State Science and Technology, 2019, 8, R109-R113.	1.8	1
9	Si/SiO2 Core/Shell Luminescent Silicon Nanocrystals and Porous Silicon Powders With High Quantum Yield, Long Lifetime, and Good Stability. Frontiers in Physics, 2019, 7, .	2.1	22
10	Calibration of the retardation inhomogeneity for the compensator-rotating imaging ellipsometer. Applied Optics, 2019, 58, 9224.	1.8	5
11	Photoetching of Porous Silicon Nanostructures in Hydrofluoric Acid Using Monochromatic Light. ECS Journal of Solid State Science and Technology, 2018, 7, P730-P735.	1.8	2
12	(Invited) Photo-Assisted Etching of Porous Silicon Nanostructures in Hydrofluoric Acid Using Monochromatic Light. ECS Transactions, 2018, 86, 71-81.	0.5	0
13	Measurement of diameter of cylindrical openings using a disk beam probe. Optical Review, 2018, 25, 656-662.	2.0	11
14	Flat-shaped microfluidic optical cell for in situ ellipsometry using glass slide as optical window component. Japanese Journal of Applied Physics, 2018, 57, 07MD01.	1.5	2
15	Extraction of properties of individual component for the retarder-linear diattenuator-retarder system and its application. , 2018, , .		0
16	Dimensional measurement of internal profile using the optical caliper. , 2018, , .		0
17	Polarization characteristics of diffraction scattering from metal rough surface. Applied Surface Science, 2017, 421, 565-570.	6.1	3
18	Rotatable Offner imaging system for ellipsometric measurement. Review of Scientific Instruments, 2017, 88, 013704.	1.3	11

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19	Optical Absorption and Quantum Confinement in Porous Silicon Nanostructures Studied by Chemical Dissolution in HF Solutions and Photoconduction. ECS Journal of Solid State Science and Technology, 2017, 6, R1-R6.	1.8	3
20	Extracting calibrated parameters from imaging ellipsometric measurement. Japanese Journal of Applied Physics, 2017, 56, 116602.	1.5	10
21	Removal of organic template of mesoporous organosilicate thin films using supercritical carbon dioxide fluids. Japanese Journal of Applied Physics, 2017, 56, 07KF02.	1.5	2
22	Structures of Cu surfaces developing in benzotriazole solutions: Effect of pH. Japanese Journal of Applied Physics, 2017, 56, 07KH01.	1.5	3
23	Extraction of polarization properties of the individual components of a layered system by using spectroscopic Mueller matrix analysis. Optics Express, 2016, 24, 9757.	3.4	2
24	(Invited) Porous Silicon Dissolution Monitoring and Optical Constants Measurement Using in Situ Photoconduction in HF. ECS Transactions, 2016, 75, 63-75.	0.5	0
25	In situ ellipsometry of Cu surfaces immersed in benzotriazoleâ€“hydrogen peroxide solutions. Japanese Journal of Applied Physics, 2016, 55, 06JG03.	1.5	6
26	Measurement of Optical Constants of Wet Porous Silicon Using In Situ Photoconduction. ECS Journal of Solid State Science and Technology, 2016, 5, P190-P196.	1.8	6
27	Polarization characteristics of scattered light from macroscopically rough surfaces. Optical Review, 2015, 22, 511-520.	2.0	6
28	Correction of large retardation window effect for ellipsometry measurements using quasi-Newton method. Applied Optics, 2015, 54, 2991.	1.8	4
29	Dispersion measurement of the electro-optic coefficientr22of the LiNbO3crystal with Mueller matrix spectropolarimetry. Japanese Journal of Applied Physics, 2015, 54, 078003.	1.5	4
30	Selective Cu filling of nanopores using supercritical carbon dioxide. Japanese Journal of Applied Physics, 2015, 54, 05EA02.	1.5	4
31	Correction of large birefringent effect of windows for in situ ellipsometry measurements. Optics Letters, 2014, 39, 1549.	3.3	4
32	General window correction method for ellipsometry measurements. Optics Express, 2014, 22, 27811.	3.4	7
33	In situ observation of Pt deposition process by using spectroscopic ellipsometry. Microelectronic Engineering, 2014, 121, 39-41.	2.4	3
34	Copper deposition in microporous silicon using supercritical fluid. Thin Solid Films, 2014, 567, 82-86.	1.8	10
35	Analysis of the quadratic retardation induced by the Pockels, Kerr, and inverse piezoelectric effects in anX-cutY-propagation LiNbO3. Japanese Journal of Applied Physics, 2014, 53, 052601.	1.5	0
36	In situ imaging ellipsometer using a LiNbO3 electrooptic crystal. Thin Solid Films, 2014, 571, 532-537.	1.8	10

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37	Fast Imaging Ellipsometer Using a LiNbO3Electrooptic Crystal. Japanese Journal of Applied Physics, 2013, 52, 036702.	1.5	7
38	Supercritical fluid deposition of copper into mesoporous silicon. Thin Solid Films, 2013, 545, 357-360.	1.8	7
39	Electro-Optic Coefficient r₅₁ of LiNbO₃ Crystal Obtained from Measurement of Retardation Induced by Square of Electric Field. Japanese Journal of Applied Physics, 2013, 52, 058001.	1.5	4
40	In-situ Spectroscopic Ellipsometry of the Cu Deposition Process from Supercritical Fluids: Evidence of an Abnormal Surface Layer Formation. Japanese Journal of Applied Physics, 2012, 51, 05EA02.	1.5	3
41	Birefringence Polarimeter Using Dual LiNbO$_{3}$ Electrooptic Crystal Modulators. Japanese Journal of Applied Physics, 2012, 51, 082201.	1.5	2
42	In-situSpectroscopic Ellipsometry of the Cu Deposition Process from Supercritical Fluids: Evidence of an Abnormal Surface Layer Formation. Japanese Journal of Applied Physics, 2012, 51, 05EA02.	1.5	5
43	Birefringence Polarimeter Using Dual LiNbO₃Electrooptic Crystal Modulators. Japanese Journal of Applied Physics, 2012, 51, 082201.	1.5	0
44	Electro-optic modulation analysis of a Y-cut Z-propagation LiNbO3 light modulator: Comparison with an X-cut Z-propagation LiNbO3 light modulator and a dual LiNbO3 crystal type modulator. Optical Review, 2011, 18, 203-211.	2.0	6
45	Polarization analysis of scattering light using a facet model. Proceedings of SPIE, 2011, , .	0.8	1
46	Tunable electro-optic crystal Fabry-Perot filter. Proceedings of SPIE, 2010, , .	0.8	1
47	Temperature characteristics of a Y-cut Z-propagation LiNbO3 light modulator for application to polarimeters. Optical Review, 2010, 17, 30-40.	2.0	6
48	Electropolymerization of Poly(para-phenylene)vinylene Films onto and Inside Porous Si layers of Different Types and Morphologies. Journal of the Electrochemical Society, 2010, 157, D648.	2.9	4
49	Direct Electropolymerization of Poly(para-phenylene)vinylene Films on Si and Porous Si. Journal of the Electrochemical Society, 2010, 157, H534.	2.9	7
50	(Invited) Electropolymerized Poly(para-phenylene)vinylene Films onto and Inside Porous Si. ECS Transactions, 2010, 28, 91-103.	0.5	0
51	Polarization properties of scattered light from macrorough surfaces. Optics Letters, 2010, 35, 595.	3.3	13
52	Stokes parameters of reflected and scattered light by a rough surface. Proceedings of SPIE, 2009, , .	0.8	4
53	Moire Metrology. , 2009, , .		1
54	Performance of a television camera system for the detection of oil slicks. Optical Engineering, 2008, 47, 093801.	1.0	0

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55	Measurement of Dispersion of Effective Electro-Optic Coefficients r₁₃ ^E and r₃₃ ^E of Non-Doped Congruent LiNbO₃ Crystal. Japanese Journal of Applied Physics, 2008, 47, 5503.	1.5	28
56	Effect of Multiple Reflections on Accuracy of Electro-Optic Coefficient Measurements. Japanese Journal of Applied Physics, 2007, 46, 7904-7911.	1.5	1
57	Measurement of Wavelength Dependence of Electro-Optic Coefficients r 22 of Non-doped and 5% MgO-doped Congruent LiNbO3 Crystals and 1.8% MgO-doped Quasi-stoichiometric LiNbO3 Crystal by Multiple Reflection Interference Method. Optical Review, 2007, 14, 194-200.	2.0	15
58	Development of television camera for detecting oil film floating on the ocean. , 2006, , .		0
59	Fast and Simultaneous Measurement of Both Birefringence and Azimuth Angle Using ay-Cut LiNbO3Phase Modulator. Japanese Journal of Applied Physics, 2006, 45, 5244-5247.	1.5	9
60	Multi-Wavelength Mueller Matrix Polarimeter. Optical Review, 2005, 12, 281-286.	2.0	5
61	Measurement of characteristics of magnetic fluid by the Mueller matrix imaging polarimeter. Optical Engineering, 2004, 43, 181.	1.0	15
62	Image detection system for 157-nm using fluorescent glass. , 2003, , .		2
63	Mueller matrix polarimeter in 157nm. , 2003, 5188, 146.		1
64	Measurement of characteristics of magnetic fluid by Mueller matrix imaging polarimeter. , 2002, 4919, 183.		0
65	Two-dimensional birefringence measurement using liquid crystal retarder for plastic disk inspection. , 2002, , .		0
66	Shadow moireÂ´ profilometry by frequency sweeping. Optical Engineering, 2001, 40, 1383.	1.0	19
67	Shadow moireÂ´ profilometry using the phase-shifting method. Optical Engineering, 2000, 39, 2119.	1.0	55
68	<title>Shadow moire profilometry using a phase-shifting method</title>. , 1999, 3740, 110.		0
69	Publisher's Note: â€œBirefringence Polarimeter Using Dual LiNbO$_{3}$ Electrooptic Crystal Modulatorsâ€• Japanese Journal of Applied Physics, 0, 51, 089202.	1.5	1
70	Hydrosilylation of High Porosity Porous Silicon with 1-Hexene in Supercritical CO2 Fluid. ECS Journal of Solid State Science and Technology, 0, , .	1.8	0
71	High Energy Limit of the Size-Tunable Photoluminescence of Hydrogen-Terminated Porous Silicon Nanostructures in HF. ECS Journal of Solid State Science and Technology, 0, , .	1.8	0
72	Electron Escape from Filled Band in Wet Porous Silicon Nanostructure Probed by Luminescence Quenching Dynamics. ECS Journal of Solid State Science and Technology, 0, , .	1.8	0